

WEST

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L3 and (radio adj frequency)	4

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- US Pre-Grant Publication Full-Text Database
- JPO Abstracts Database
- EPO Abstracts Database
- Derwent World Patents Index
- IBM Technical Disclosure Bulletins ▼

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L4

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DB=USPT; PLUR=YES; OP=ADJ

<u>L4</u>	L3 and (radio adj frequency)	4	<u>L4</u>
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END OF SEARCH HISTORY

WEST[Generate Collection](#)[Print](#)**Search Results - Record(s) 1 through 4 of 4 returned.**☐ 1. Document ID: US 6355943 B1

L4: Entry 1 of 4

File: USPT

Mar 12, 2002

US-PAT-NO: 6355943

DOCUMENT-IDENTIFIER: US 6355943 B1

** See image for Certificate of Correction **

TITLE: Thin film transistor, method of producing the same, liquid crystal display, and thin film forming apparatus

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments	Claims	KWIC
Drawn Desc	Image										

☐ 2. Document ID: US 6338990 B1

L4: Entry 2 of 4

File: USPT

Jan 15, 2002

US-PAT-NO: 6338990

DOCUMENT-IDENTIFIER: US 6338990 B1

TITLE: Method for fabricating thin-film transistor

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments	Claims	KWIC
Drawn Desc	Image										

☐ 3. Document ID: US 5879973 A

L4: Entry 3 of 4

File: USPT

Mar 9, 1999

US-PAT-NO: 5879973

DOCUMENT-IDENTIFIER: US 5879973 A

TITLE: Method for fabricating thin-film transistor

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments	Claims	KWIC
Drawn Desc	Image										

☐ 4. Document ID: US 5470768 A

L4: Entry 4 of 4

File: USPT

Nov 28, 1995

US-PAT-NO: 5470768

DOCUMENT-IDENTIFIER: US 5470768 A

TITLE: Method for fabricating a thin-film transistor

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments	Claims	K00C
Draw. Desc	Image										

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Terms	Documents
L3 and (radio adj frequency)	4

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WEST[Generate Collection](#)[Print](#)**Search Results - Record(s) 1 through 4 of 4 returned.**☐ 1. Document ID: US 6538388 B2

L2: Entry 1 of 4

File: USPT

Mar 25, 2003

US-PAT-NO: 6538388

DOCUMENT-IDENTIFIER: US 6538388 B2

TITLE: Plasma processing apparatus suitable for power supply of higher frequency

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments
Draw Desc	Image								

[KWC](#)☐ 2. Document ID: US 6355943 B1

L2: Entry 2 of 4

File: USPT

Mar 12, 2002

US-PAT-NO: 6355943

DOCUMENT-IDENTIFIER: US 6355943 B1

** See image for Certificate of Correction **

TITLE: Thin film transistor, method of producing the same, liquid crystal display, and thin film forming apparatus

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments
Draw Desc	Image								

[KWC](#)☐ 3. Document ID: US 6337292 B1

L2: Entry 3 of 4

File: USPT

Jan 8, 2002

US-PAT-NO: 6337292

DOCUMENT-IDENTIFIER: US 6337292 B1

TITLE: Method of forming silicon oxide layer and method of manufacturing thin film transistor thereby

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments
Draw Desc	Image								

[KWC](#)

☐ 4. Document ID: US 5330578 A

L2: Entry 4 of 4

File: USPT

Jul 19, 1994

US-PAT-NO: 5330578

DOCUMENT-IDENTIFIER: US 5330578 A

TITLE: Plasma treatment apparatus

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments	KWIC
Draw	Desc	Image								

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Terms	Documents
L1 and susceptor adj electrode	4

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☐ 1. Document ID: US 6534395 B2

L3: Entry 1 of 15

File: USPT

Mar 18, 2003

US-PAT-NO: 6534395

DOCUMENT-IDENTIFIER: US 6534395 B2

TITLE: Method of forming graded thin films using alternating pulses of vapor phase reactants

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments
Draw Desc	Image								

[KIMC](#)☐ 2. Document ID: US 6444507 B1

L3: Entry 2 of 15

File: USPT

Sep 3, 2002

US-PAT-NO: 6444507

DOCUMENT-IDENTIFIER: US 6444507 B1

TITLE: Fabrication process for thin film transistors in a display or electronic device

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments
Draw Desc	Image								

[KIMC](#)☐ 3. Document ID: US 6444506 B1

L3: Entry 3 of 15

File: USPT

Sep 3, 2002

US-PAT-NO: 6444506

DOCUMENT-IDENTIFIER: US 6444506 B1

TITLE: Method of manufacturing silicon thin film devices using laser annealing in a hydrogen mixture gas followed by nitride formation

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments
Draw Desc	Image								

[KIMC](#)

☐ 4. Document ID: US 6355943 B1

L3: Entry 4 of 15

File: USPT

Mar 12, 2002

US-PAT-NO: 6355943

DOCUMENT-IDENTIFIER: US 6355943 B1

** See image for Certificate of Correction **

TITLE: Thin film transistor, method of producing the same, liquid crystal display, and thin film forming apparatus

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments
Draw Desc	Image								

KVMC

☐ 5. Document ID: US 6338990 B1

L3: Entry 5 of 15

File: USPT

Jan 15, 2002

US-PAT-NO: 6338990

DOCUMENT-IDENTIFIER: US 6338990 B1

TITLE: Method for fabricating thin-film transistor

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments
Draw Desc	Image								

KVMC

☐ 6. Document ID: US 6149984 A

L3: Entry 6 of 15

File: USPT

Nov 21, 2000

US-PAT-NO: 6149984

DOCUMENT-IDENTIFIER: US 6149984 A

TITLE: Laser irradiation method

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments
Draw Desc	Image								

KVMC

☐ 7. Document ID: US 6124154 A

L3: Entry 7 of 15

File: USPT

Sep 26, 2000

US-PAT-NO: 6124154

DOCUMENT-IDENTIFIER: US 6124154 A

TITLE: Fabrication process for thin film transistors in a display or electronic device

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments
Draw Desc	Image								

KMIC

☐ 8. Document ID: US 5925421 A

L3: Entry 8 of 15

File: USPT

Jul 20, 1999

US-PAT-NO: 5925421

DOCUMENT-IDENTIFIER: US 5925421 A

TITLE: Laser irradiation method

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments
Draw Desc	Image								

KMIC

☐ 9. Document ID: US 5888855 A

L3: Entry 9 of 15

File: USPT

Mar 30, 1999

US-PAT-NO: 5888855

DOCUMENT-IDENTIFIER: US 5888855 A

TITLE: Method of manufacturing active matrix display

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments
Draw Desc	Image								

KMIC

☐ 10. Document ID: US 5879973 A

L3: Entry 10 of 15

File: USPT

Mar 9, 1999

US-PAT-NO: 5879973

DOCUMENT-IDENTIFIER: US 5879973 A

TITLE: Method for fabricating thin-film transistor

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments
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KMIC

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L1 and (gate adj electrode) and (susceptor) and (plasma) and silane and ammonia	15

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☐ 11. Document ID: US 5840600 A

L3: Entry 11 of 15

File: USPT

Nov 24, 1998

US-PAT-NO: 5840600

DOCUMENT-IDENTIFIER: US 5840600 A

TITLE: Method for producing semiconductor device and apparatus for treating semiconductor device

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments
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[KIMC](#)☐ 12. Document ID: US 5817549 A

L3: Entry 12 of 15

File: USPT

Oct 6, 1998

US-PAT-NO: 5817549

DOCUMENT-IDENTIFIER: US 5817549 A

TITLE: Method for manufacturing a semiconductor device

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments
Draw Desc	Image								

[KIMC](#)☐ 13. Document ID: US 5525550 A

L3: Entry 13 of 15

File: USPT

Jun 11, 1996

US-PAT-NO: 5525550

DOCUMENT-IDENTIFIER: US 5525550 A

TITLE: Process for forming thin films by plasma CVD for use in the production of semiconductor devices

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments
Draw Desc	Image								

[KIMC](#)☐ 14. Document ID: US 5470768 A

L3: Entry 14 of 15

File: USPT

Nov 28, 1995

US-PAT-NO: 5470768

DOCUMENT-IDENTIFIER: US 5470768 A

TITLE: Method for fabricating a thin-film transistor

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments
Draw Desc	Image								

KMC

☐ 15. Document ID: US 4585671 A

L3: Entry 15 of 15

File: USPT

Apr 29, 1986

US-PAT-NO: 4585671

DOCUMENT-IDENTIFIER: US 4585671 A

TITLE: Formation process of amorphous silicon film

Full	Title	Citation	Front	Review	Classification	Date	Reference	Sequences	Attachments
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KMC

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Terms	Documents
L1 and (gate adj electrode) and (susceptor) and (plasma) and silane and ammonia	15

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